## WHAT IS CLAIMED IS: 1 2 3 1. An optical switch array assembly comprising: 4 a silicon substrate, an optical switch array disposed in the silicon substrate, 5 6 a driving circuit integrated in the silicon substrate with the optical 7 switch array and forcing the optical switches on and off, and a plurality of holes on the backside of the silicon substrate each 8 9 aligned with an optical switch and guiding an optical beam to the optical switch. 10 The state that the state that the state the state that 11 2. An optical switch array assembly of claim 1 further comprising an 12 addressing circuit integrated in the silicon substrate with the optical switch array 13 and locating each optical switch. The Hall of the test from the first 14 3. 15 An optical switch array assembly of claim 1 further comprising a glass 16 plate mounted on the top of the silicon substrate. 17 4. 18 An optical switch array assembly of claim 1 further comprising a plurality 19 of DNA probes disposed on the surface of the glass plate. 20 5. 21 An optical switch array assembly of claim 1 further comprising a plurality 22 of hybridized DNA probes disposed on the surface of the glass plate. 23

24

An optical switch array assembly according to claim 1, where said

6.

1

24

substrate,

1

24

depositing a first mirror layer on the surface of the anti-reflective

1	15. A method of making an optical switch array assembly, according to
2	claim 11 where said first mirror layer is a silicon nitride layer.
3	
4	16. A method of making an optical switch array assembly, according to
5	claim 11 where said sacrificial layer is a silicon dioxide layer.
6	
7	17. A method of making an optical switch array assembly, according to
8	claim 11 where said sacrificial layer is an aluminum layer.
9	
10	18. A method of making an optical switch array assembly, according to
11	claim 11 where said second mirror is an amorphous silicon carbide layer.
12	
13	19. A method of making an optical switch array assembly, according to
14	claim 11 where said second mirror layer is a silicon nitride layer.
15	
16	20. A method of making an optical switch array assembly, according to
17	claim 11 where said refilled trenches are filled with silicon dioxide.
18	
19	21. A method of making an optical switch array assembly, according to
20	claim 11 where said refilled trenches are filled with an amorphous silicon-
21	silicon dioxide-amorphous silicon sandwiched plug.
22	
23	
24	

22. A method of making an optical switch array assembly, according to claim 11 where said refilled trenches are filled with an amorphous silicon-silicon dioxide-amorphous silicon sandwiched plug.